

Supplementary information

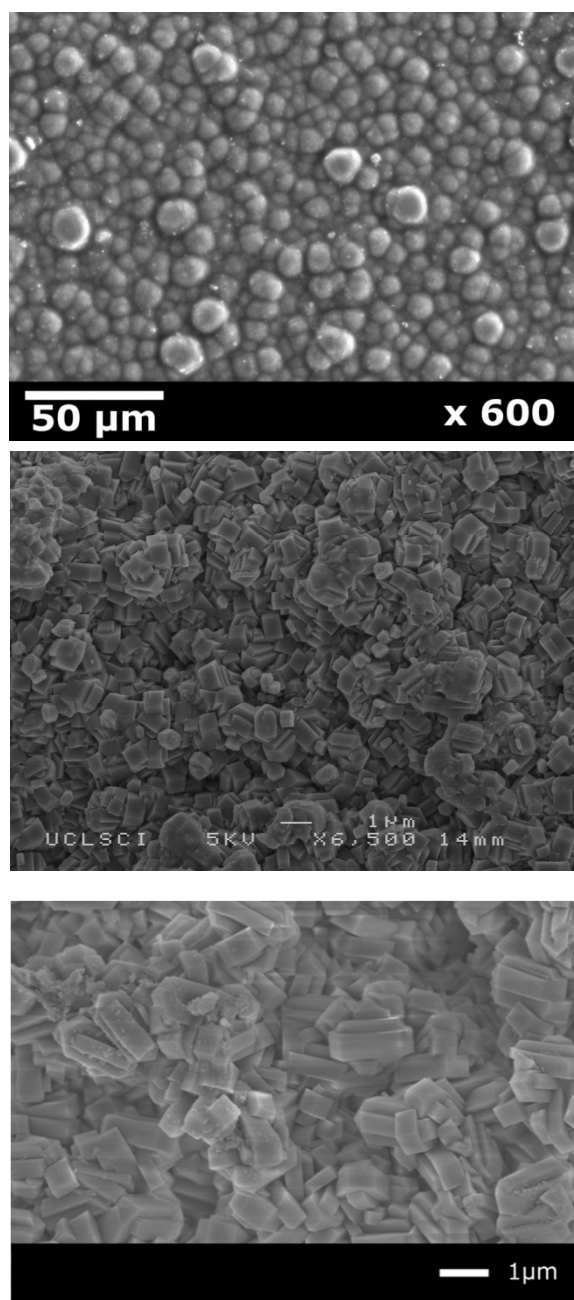


Figure S1 . Typical SEM micrograph of silica particles deposited on silicon substrate using CVD process, shown on the top. This supported film was used for conversion to the zeolite film which is shown in the middle. In the bottom we show TS-1 film on silicon.